

Main Options of A12 Prober



- RFID/ FOUP ID Reader
- OCR wafer ID reader (Top / Bottom)
- 3 Buffer trays for wafer storage
- Loader mini-environment
- Automatic probe card changer
- Chuck: High/Low/Normal temperature
- Real time map data
- One touch contact probing
- PMAI: Probe Mark Auto-Inspection
- PLV: Prober Log Viewer
- RCS: Remote Control System
- DUT Editor & Recipe Editor

Specifications of A12 Automatic Probe Station

Main body	X-Y axis	Repeatability : $\leq \pm 1\mu\text{m}$
		Resolution: $0.1\mu\text{m}$
		Probing area: X $\pm 170\text{mm}$, Y -180 , +600mm
		Maximum speed : 240mm/s
	Z axis	Repeatability : $\leq \pm 1\mu\text{m}$
		Resolution: $0.1\mu\text{m}$
θ axis	Movement: 0 ~ 80mm	
	Rotation Range : $\pm 10^\circ$	
Loader	Cassette / Wafer Size	$\Phi 200\text{mm}$, $\Phi 300\text{mm}$
Monitor		15 inch High-resolution color LCD
Facility Requirement		Power :50/60Hz AC 220V, CDA: 0.4 to 0.8Mpa , Vacuum: -53 to -100Kpa
Dimensions		WxDxH: 1595 x 1675 x 1500 mm

深圳市森美协尔科技有限公司
SEMISHARE CO.,LTD.

Address:3rd Floor, Building 4, Innovation Port of Hanyuwan, Fuhai Street, Baoan District, Shenzhen
Tel:0755-2690 6952 Fax:0755-8529 9649
E-mail:sales@semishare.com
Web:www.semishareprober.com



Official Website



Official WeChat

SEMISHARE

A12 Automatic Probe Station



Advanced wafer prober manufacturer





SEMISHARE-A12 Automatic Probe Station

A12 is a 12-inch (compatible with 8-inch) high-performance wafer test probe station that completes the wafer WAT/CP test through precise contact between probe cards and wafer PAD points. The device is easy-to-use and has superior mechanical stability, which can provide customers with a low-cost and high-yield wafer test solution and meet the test requirements of different customers such as wafer factories, chip package factories, test factories, etc.

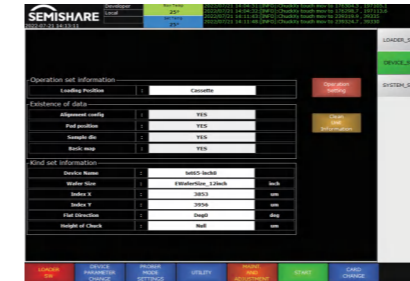
The innovative A12 probe station makes new upgrades and improvements in the technical fields of automatic wafer up-and-down loading and conveying, micrometer-level full closed-loop motion control, wafer automatic and accurate probe alignment, visual automatic and accurate calibration, high-speed feedback communication, and data information processing. The device adopts a wafer probe test technique with high stability.

Product Features

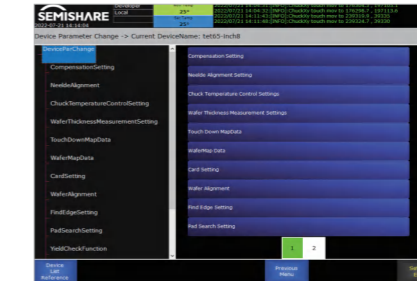
- Super high test precision and test speed, greatly improve productivity benefits
- Automatic wafer up-and-down loading and conveying
- Micrometer-level full closed-loop motion control
- 7*24 on-chip detection
- High strength and low center of gravity design
- Friendly Graphic User Interface

Friendly Graphic User Interface

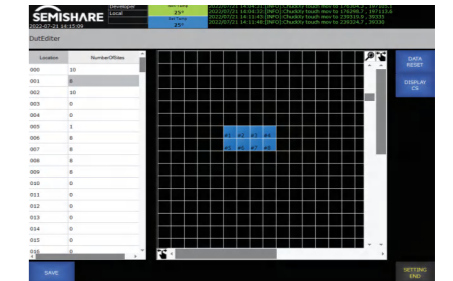
Initial Information



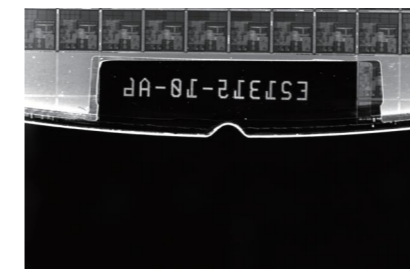
Recipe Parameter Settings



Multi DUT Location Edit



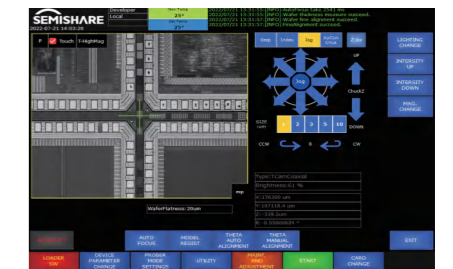
Wafer ID Reading



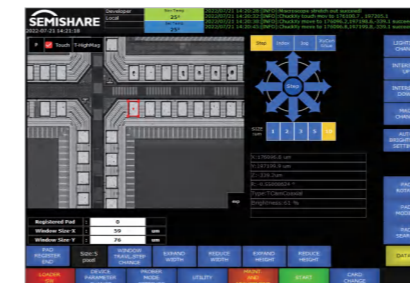
Wafer Edge Measurement



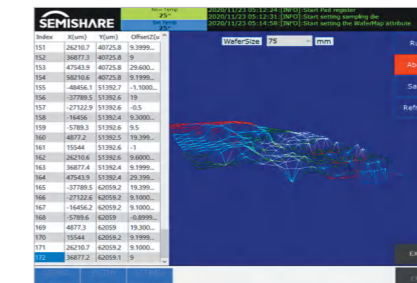
Index & Z height



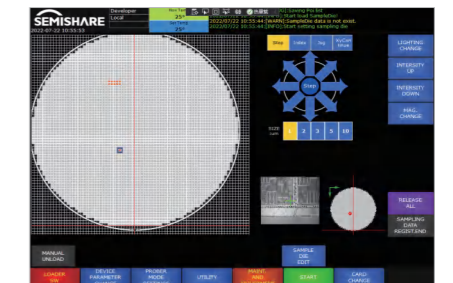
PAD Registration



Contact Compensation



Real-time Wafer Map Data



Software Functions

